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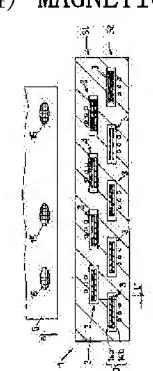
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MINAMITANI TAMOTSU

(54) MAGNETIC SENSOR



(57) Abstract:

PROBLEM TO BE SOLVED: To provide a magnetic sensor capable of reading magnetism in the whole range of a detection range, heightening the magnetic pattern detection sensitivity even if a magnetic pattern array is changed, and preventing generation of a cross talk.

SOLUTION: Element rows S1, S2 formed by arraying a plurality of magnetic resistance elements 3 along the crossing direction at a prescribed angle with the passing direction of an analyte 6 having the magnetic pattern 15 are installed in the shifted state in the passing direction of the analyte 6. Each magnetic resistance element 3 in one element row has an array form wherein its magnetic induction region 10 overlap that of the magnetic resistance element 3 in the other element row in the passing direction of the analyte 6 so that the whole region where the analyte 6 passes becomes the magnetic induction region in the array direction of the magnetic resistance elements 3.

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[Claim(s)]

[Claim 1] Each magnetic resistance element [in / the element array which arranged two or more magnetic resistance elements along the direction which crosses at a predetermined include angle to the passage direction of the analyte which has a magnetic pattern is shifted in the passage direction of said analyte, and / in two or more successive installation **** / said one element array] is a magnetometric sensor with which it is characterized by what is considered as the array gestalt with which a magneto induction field laps mutually towards said analyte passing to the magnetic resistance element in other element arrays.

[Claim 2] The magneto induction field of each of each magnetic resistance element [in / in a magnetometric sensor according to claim 1, said element arrays are two trains, and / one side of the element array of said two trains] and the magneto induction field of each of each magnetic resistance element in another side of the element array of said two trains are a magnetometric sensor characterized by what is considered as the array gestalt which laps mutually in the direction through which said analyte passes.

[Claim 3] It is the magnetometric sensor characterized by what said magnetometric sensor has the case in the magnetometric sensor according to claim 1 or 2, two or more individual receipt slots which contain two or more magnetic resistance elements of each which constitute said each element array in said case according to an individual are prepared, and each magnetic resistance element of each of said element array is contained for by said receipt slot classified by each.

[Claim 4] It is the magnetometric sensor according to claim 1 characterized by what said magnetometric sensor has the case in the magnetometric sensor according to claim 1 or 2, the common receipt slot which carries out the common receipt of two or more magnetic resistance elements which constitute each element array for said every element array in said case is prepared, and each magnetic resistance element of each of said element array is contained for by said each of each common receipt slot.

[Claim 5] The predetermined include angle which the direction where a magnetic resistance element is arranged with said element array in a magnetometric sensor given in either of claims 1-4, and the passage direction of said analyte cross is a magnetometric sensor characterized

by what is been a rectangular cross or the include angle which intersects perpendicularly mostly.

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DETAILED DESCRIPTION

[Detailed Description of the Invention]

[0001]
[Field of the Invention] This invention

[Field of the Invention] This invention relates to a magnetometric sensor and relates to the magnetometric sensor with which two or more magnetic resistance elements are arranged along the direction which crosses at a predetermined include angle in more detail to the passage direction of the analyte by which magnetic detection is carried out, for example, the direction which intersects perpendicularly.

[0002]

[Description of the Prior Art] With reference to drawing 7, a magnetometric sensor 1 and the magnetic card 6 as analyte which should be detected by this magnetometric sensor 1 are explained.

[0003] A magnetic card 6 has two or more magnetic patterns 15 which corresponded to the longitudinal direction of the detection side of a magnetometric sensor 1 so that it might meet in what was illustrated to drawing 7. This magnetic pattern 15 is equivalent to the data recorded on a magnetic card 6.

[0004] A magnetometric sensor 1 has two or more magnetic resistance elements 3 which have similarly arranged said magnetic pattern 15 possible [reading] along with the longitudinal direction of the detection side.

[0005] the time of a magnetic card 6 moving in the direction of arrow-head a of drawing 7, approaching a magnetometric sensor 1, and passing through the detection side top — each magnetic resistance element 3 of

a magnetometric sensor 1 — each — each magnetic pattern 15 of a magnetic card 6 — it is alike, respectively, magneto induction is carried out individually, and the detection output corresponding to the magneto induction is outputted. Each detection output of a magnetometric sensor 1 is given to the processing circuit which is not illustrated [which carries out signal processing], and the record data of a magnetic card 6 are processed by this.

[0006] Array spacing of each magnetic pattern 15 in such a magnetic card 6 and each magnetic resistance element 3 in a magnetometric sensor 1 is made predetermined relation, and it enables it to detect the data currently recorded on the magnetic card 6 with the gestalt of the magnetic pattern 15 with a magnetometric sensor 1.

[0007] When spacing between ***** magnetic resistance elements was large and change arises at array spacing of the magnetic pattern 15 in a magnetic card 6, correspondence relation with the magnetic resistance element 3 in the magnetic pattern 15 and magnetometric sensor 1 is broken down, and it becomes impossible for a magnetometric sensor 1 to detect the magnetic pattern 15 of a magnetic card 6 correctly in such structure.

[0008] Then, the applicant for this patent has already proposed the magnetometric sensor which can detect each magnetic pattern certainly in JP, 5-332703, A, even if array spacing of a magnetic pattern is changed in this way.

[0009] As drawing 7 shows, near the center section of the whole surface used as the detection side of a case 2, this magnetometric sensor forms the long slot 20 where a long side meets in a case 2 and this direction, and arranges and consists of gestalten which adjoin each other so that this long slot 20 may be mutually contacted on the direction straight line of a long side in two or more magnetic resistance elements 3.

[0010] In arranging so that spacing of the magneto induction section 10 in each adjacent magnetic resistance elements 3 and 3 and ten comrades may become narrower than the width of face of the magnetic pattern 15 at this time, even if the magnetic pattern of a magnetic card is changed, it is expectable to detect that magnetic pattern.

[0011]

[Problem(s) to be Solved by the Invention] By the way, in order that an applicant for this patent might aim at amelioration of the above-mentioned magnetometric sensor, he repeated research further and found out the technical problem explained below about the magnetometric sensor. [0012] As drawing 4 shows, the magneto induction section 10 of each magnetic resistance element 3 used for the above-mentioned magnetometric

sensor 1 is installed in a longitudinal direction side by side, where series connection of two or more unit magnetic force sencors j is carried out, it constitutes the admiration magnetic body trains 14a and 14b, further, separates predetermined spacing mutually forward and backward, and forms the pair of these admiration magnetic body trains 14a and 14b on a substrate 17.

[0013] However, in each magnetic resistance element 3, as shown in drawing 4, since there is no structure which carries out a magnetosensitive **** magnetoelectric conversion, in the field between the edge in the longitudinal direction of the magneto induction section 10, and the edge section in the longitudinal direction of a substrate 17, the field is the non-[magnetic] influence field L which cannot detect the magnetic pattern 15.

[0014] Therefore, when this magnetic resistance element 3 is arranged by the longitudinal-direction single tier like the above-mentioned magnetometric sensor, the non-[magnetic] influence field L of the non-[magnetic] influence field L of a magnetic resistance element 3 (for example, a non-[magnetic] influence field is generated by die length of about 125 micrometers), this magnetic resistance element 3, and the adjacent magnetic resistance element 3 will be totaled, and the fairly big non-[magnetic] influence field H (refer to drawing 7) will be formed.

[0015] On the other hand, modification of the correspondence physical relationship of array spacing of the magnetic pattern 15 of a magnetic card 6, and a magnetic pattern and a magnetic resistance element 3 generates what shifts to the broken-line location which does not carry out a right pair from the continuous-line location as for which the location of the magnetic pattern 15 in a magnetic card 6 carries out a right pair to the magneto induction section 10, for example, as shown in drawing 7. Consequently, there is a possibility that the detection output of the magnetic pattern by the magnetometric sensor may decline, and detection sensibility may become low.

[0016] Moreover, when it approaches so that it may straddle between the magnetic resistance elements to which a magnetic pattern adjoins a longitudinal direction since the magnetic resistance element is arranged by the longitudinal direction single tier of a detection side in the case of this magnetometric sensor, the so-called cross talk with which the detection output to the same magnetic pattern is given to coincidence from each of both magnetic resistance elements in a magnetic-card data-processing circuit occurs, and fault is caused to processing of the record data of the magnetic card in this processing

circuit.

[0017] Therefore, this invention makes it for magnetic pattern detection sensibility to be raised and to make it said cross talk not occur, even if it makes reading of the MAG possible in all the range of the detection range and there is array modification of a magnetic pattern the technical problem which should be solved in the magnetometric sensor. [0018]

[Means for Solving the Problem] This invention is characterized by shifting the element array which arranged two or more magnetic resistance elements along the direction which crosses at a predetermined include angle to the passage direction of the analyte which has a magnetic pattern in the passage direction of said analyte, and making each magnetic resistance element in said one element array into the array gestalt with which a magneto induction field laps mutually with two or more successive installation **** towards said analyte passing to the magnetic resistance element in other element arrays.

[0019] The magneto-induction field of each of each magnetic resistance element in the element array of two or more trains which have been shifted and arranged in the passage direction of analyte according to this invention can detect the magnetic pattern, even if it compares and array spacing of the magnetic pattern of analyte is changed, since all the fields through which are considering as the array gestalt which laps mutually in the direction through which analyte's passes, and analyte passes in the array direction of a magnetic resistance element turn into a magneto-induction field. It seems that therefore, neither the fall of a detection output nor the fall of detection sensibility is caused.

[0020] Moreover, since said each element array is predetermined ******* carried out to said detection direction and is prepared, it is lost that the cross talk with which the magnetic resistance element of each element array detects analyte to coincidence occurs, and detection of a magnetic pattern can be ensured.

[0021] This invention is desirable, said element arrays are two trains and the magneto induction field of each of each magnetic resistance element in one side of the element array of said two trains and the magneto induction field of each of each magnetic resistance element in another side of the element array of said two trains are made into the array gestalt which laps mutually in the direction through which said analyte passes.

[0022] In this case, even if array spacing of the magnetic pattern of analyte is changed, while that magnetic pattern is certainly detectable and becoming structurally easy, it can constitute from element arrays

being two trains in a compact.

[0023] This invention is desirable, said magnetometric sensor has the case, two or more individual receipt slots which contain two or more magnetic resistance elements of each which constitute said each element array according to an individual are established in said case, and each magnetic resistance element of each of said element array is contained by said receipt slot classified by each.

[0024] This invention is desirable, said magnetometric sensor has the case, the common receipt slot which carries out the common receipt of two or more magnetic resistance elements which constitute each element array is established in said case for said every element array, and each magnetic resistance element of each of said element array is contained by said each of each common receipt slot.

[0025] The predetermined include angle which this invention is desirable and the direction where a magnetic resistance element is arranged with said element array, and the passage direction of said analyte cross is a rectangular cross or an include angle which intersects perpendicularly mostly.

[0026]

[Embodiment of the Invention] Hereafter, it explains based on the gestalt of the operation which shows the detail of this invention to a drawing.

[0027] The sectional view where the sectional view where drawing 1 thru/or drawing 4 start the operation gestalt of this invention, drawing 1 meets the perspective view of the magnetometric sensor of the gestalt of this operation, and drawing 2 meets the A-A line of drawing 1, and drawing 3 meet the B-B line of drawing 1, and drawing 4 are the top views of a magnetic resistance element.

[0028] With reference to drawing 1 thru/or drawing 4, the magnetometric sensor 1 of the gestalt of this operation has the case 2 of a long mold, two or more magnetic-resistance-element 3 --, and the metal covering 4 and the permanent magnet 5 for bias.

[0029] A case 2 has a long picture configuration to the direction through which the magnetic card 6 as analyte passes in a rectangular cross or the direction (the array direction mentioned later) which intersects perpendicularly mostly. Two or more magnetic-resistance-element receipt slots 7 are established in the whole surface of a case 2, and receipt immobilization of the magnetic resistance element 3 is carried out in this receipt slot 7, respectively. The depth of this magnetic-resistance-element receipt slot 7 is made deeper than the component thickness of a magnetic resistance element 3.

[0030] a case 2 -- on the other hand, the permanent magnet receipt slot 8 is established in a side, and receipt immobilization of the permanent magnet 5 single into this receipt slot 8 is carried out.

[0031] The whole surface side of a case 2 is covered with the metal covering 4. Furthermore, two or more terminal pins 9 are transfixed to the case 2.

[0033] If it explains in full detail, as the magneto induction section 10 is shown in drawing 4, it is prepared in the condition that the magnetic force sencors 14a and 14b of two trains carry out phase opposite, said terminals 11 and 12 are connected to the both ends of one magnetic force sencor 14a, respectively, said terminal 13 is connected to the end of magnetic force sencor 14b of another side, and said terminal 12 is connected to the other end of magnetic force sencor 14b of another side.

[0034] And the lead terminals 16, 17, and 18 connected to each terminals 11, 12, and 13 are connected to said terminal pin 9 prepared in the case 2, respectively.

[0035] this — this magnetometric sensor 1 — two or more magnetic resistance elements 3 — respectively — since — the detection output of the magnetic information from the magnetic card 6 as analyte is obtained according to an individual.

[0036] In the above configuration, it has the description in the next configuration with the gestalt of this operation. That is, with the gestalt of this operation, two or more magnetic-resistance-element receipt slots 7 are shifted to predetermined spacing by ****** 2 train, and a location is alternately carried out in the direction which intersects perpendicularly to the direction over the magnetometric sensor 1 of a magnetic card 6 through which it passes, and they are established in it. And it sets alternately, and the magnetic-resistance-element receipt slot 7 of each train is formed so that a magnetic card 6 may lap in the following relation in said direction which passes through the detection side top of a magnetometric sensor 1.

[0037] that is, it is shown in drawing 1 and drawing 2 -- as -- the

magnetic-resistance-element receipt slot 7 of each element array -- said two or more magnetic resistance elements 3 by being alike, respectively and containing the magnetic resistance element 3 As opposed to each magneto induction section 10 and 10 two magnetic resistance elements 3 and 3 in [in / it is divided into two element arrays S1 and S2, respectively that it is also at the magnetic resistance element of a predetermined number, and / each element arrays S1 and S2] one element array S1 -- It considers as the array gestalt with which the magneto induction section 10 of the magnetic resistance element 3 in the element array S2 of another side laps in the direction (direction which the arrow head a in drawing 2 shows) in which it passes a magnetometric sensor 1 since a magnetic card 6 is detection of the magnetic pattern 15. [0038] Here, as drawing 4 shows a magnetic resistance element 1, the magneto induction section 10 is formed along said predetermined direction on the necessary substrate 19, and the field between the bothends edge in said predetermined direction of a substrate 19 and each longitudinal direction both-ends edge of the magneto induction section 10 is the non-[magnetic] influence field L. Moreover, the opposite distance of both the magneto induction section of the magnetic resistance element which adjoins each other in the predetermined direction [in each element array] is set below to the detection die length (that is, the die length of the range in which the magnetic pattern 15 is formed) of the magnetic card 6 as analyte. Here, the magneto induction section 10 shows a magneto induction field. [0039] two magnetic resistance elements [in / moreover / one element array S1] 3 and 3 -- it considers as the array gestalt with which the magneto induction section 10 of the magnetic resistance element 3 in the element array S2 of another side laps in the direction which passes the magnetometric sensor 1 of a magnetic card 6 to each magneto induction section 10 and 10.

[0040] Therefore, in the case of the magnetometric sensor 1 concerning the gestalt of this operation, a magnetic resistance element 3 adjoins each other in the predetermined direction, and two or more arrangement is carried out. Even if a big non-[magnetic] influence field is formed in the predetermined direction concerned of those non-[magnetic] influence fields and array spacing of the magnetic pattern 15 is changed by the magnetic-card 6 side To the magneto induction section 10 of each of two magnetic resistance elements in one element array according to the array gestalt with which the magneto induction section 10 of the magnetic resistance element in the element array of another side laps to the passage direction of said magnetic card 6 In the whole breadth range

through which the magnetic pattern 15 of a magnetic card 6 passes, since there is no field which cannot detect the magnetic pattern 15, the magnetic pattern 15 is detectable with a certainly sufficient precision. It seems that neither the fall of a detection output nor the fall of detection sensibility is caused even when field L' with which each train S1 and the magneto induction section 10 between S2 lap especially is on a detection pattern.

[0041] Moreover, since said each element arrays S1 and S2 are predetermined ****** carried out to said passage direction of a magnetic card 6 and are prepared, it is lost that the cross talk with which the magnetic resistance element 3 of each element arrays S1 and S2 detects analyte to coincidence occurs, and detection of the magnetic pattern 15 can be ensured.

[0042] This invention is not limited to an above-mentioned operation gestalt, and can consider various application and deformation. [0043] (1) In the case of the above-mentioned operation gestalt, the magnetic-resistance-element receipt slot was an individual receipt slot which contains each of each magnetic resistance element according to an individual, but The common receipt slot 20 which carries out the common receipt of two or more magnetic resistance elements 3 which constitute one element array as drawing 5 shows, The common receipt slot 21 which carries out the common receipt of each makes a longitudinal direction carry out a predetermined distance location gap, and is established in it. two or more magnetic resistance elements 3 which constitute the element array of said another side -- said each common receipt slots 20 and 21 -- respectively -- alike -- the magnetic resistance element 3 of each of said element arrays S1 and S2 -- each may be contained. In this case, while having contained so that a magnetic resistance element 3 may contact mutually [***** things do not have a spacer etc. and] in each element arrays S1 and S2 Because the common receipt slots 20 and 21 are carrying out the predetermined distance location gap by the longitudinal direction The magneto induction section 10 which serves as a magneto induction field of the magnetic resistance element 3 of an element array S1 in the passage direction in case analyte moves in the direction of arrow-head a and the magnetometric sensor 1 is passed for magnetic detection, Since the magneto induction section 10 used as the magneto induction field of the magnetic resistance element 3 of an element array S2 laps, the field which cannot carry out magnetic detection in the passage field of the analyte in the direction in which the magnetic resistance element 3 is arranged is lost, and can improve [precision] magnetic detection.

- [0044] (2) In the case of the above-mentioned operation gestalt, for the case of a magnetometric sensor to serve as a long picture, but what is necessary is just the case which does not need to be limited to this and can contain a magnetic resistance element.
- [0045] (3) Although a magnetic resistance element is arranged in the direction which intersects perpendicularly to the passage direction of analyte in the case of an above-mentioned operation gestalt and the element array is constituted, it may cross at the predetermined include angle which the need that the direction of the element array intersects perpendicularly to the passage direction of analyte does not not necessarily have, and becomes slanting to the passage direction of analyte.
- [0046] (4) In the case of the above-mentioned operation gestalt, it is the gestalt by which one magnetic resistance element is contained in one magnetic-resistance-element receipt slot, but you may make it make one magnetic-resistance-element receipt slot 22 contain two or more magnetic-resistance-element 3 --, as there is not necessarily no need of making one magnetic-resistance-element receipt slot containing one magnetic resistance element, for example, drawing 6 shows. In this case, a spacer is made for a list to intervene between the ***** magnetic resistance elements 3 in the same element array between an element array S1 and S2.
- [0047] (5) In the case of an above-mentioned operation gestalt, the magneto induction section 10 of each magnetic resistance element 3 used for the above-mentioned magnetometric sensor 1 For example, although what installed in the longitudinal direction side by side where series connection of two or more unit magnetic force sencors j is carried out, constituted the magnetosensitive objects 14a and 14b, separated the pair of these magnetosensitive objects 14a and 14b, and formed predetermined spacing for it on the substrate 17 mutually forward and backward further was shown as drawing 4 showed The magnetic resistance element constituted so that a magnetosensitive object might become width with 1 relation is sufficient.
- [0048] (6) In the case of the above-mentioned operation gestalt, the magnetic card was shown as analyte, but it may not be limited to a magnetic card and a stick-like magnetic-recording medium etc. may be used.
- [0049] (7) It is not necessary to necessarily set up the opposite distance of both the magneto induction section of the magnetic resistance element which adjoins each other in the predetermined direction [in each element array] in this way, and with an above-

mentioned operation gestalt, although [distance] set below to the detection die length of the magnetic card 6 as analyte, also when the opposite distance is longer than the detection die length of analyte, it is included in the invention in this application.

[0050]

[Effect of the Invention] Even if there are a metaphor and array modification of a magnetic pattern since non-detecting area is lost according to this invention as explained above, magnetic pattern detection sensibility is raised and reading of the MAG becomes possible in all the range of the detection range. Moreover, a cross talk can be prevented from generating.

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DESCRIPTION OF DRAWINGS

[Brief Description of the Drawings]

[Drawing 1] The perspective view of the magnetometric sensor concerning the operation gestalt of this invention

[Drawing 2] The sectional view which meets the A-A line of drawing 1

[Drawing 3] The sectional view which meets the B-B line of drawing 1

[Drawing 4] The top view of a magnetic resistance element

[Drawing 5] The top view of the important section of the magnetometric sensor concerning other operation gestalten of this invention

[Drawing 6] The top view of the important section of the magnetometric sensor concerning other operation gestalten of this invention

[Drawing 7] Drawing showing the relation between a magnetic card and the conventional magnetometric sensor

[Description of Notations]

- 1 Magnetometric Sensor
- 3 Magnetic Resistance Element

- 6 Magnetic Card (Analyte)
- 10 Magneto Induction Section (Magneto Induction Field)
- 15 Magnetic Pattern
- S1, S2 Element array

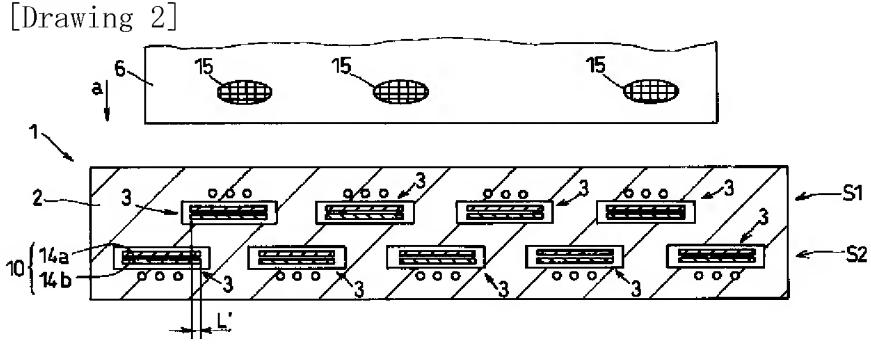
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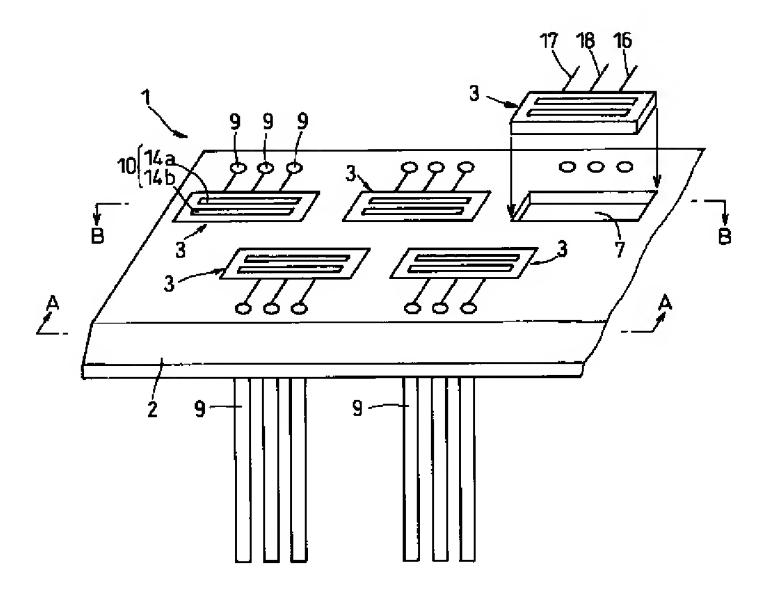
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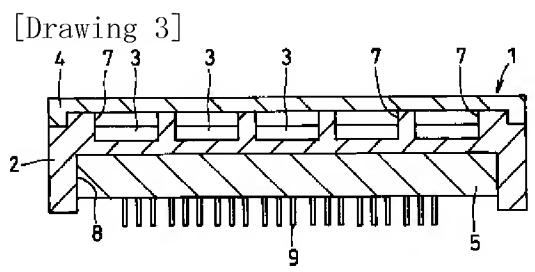
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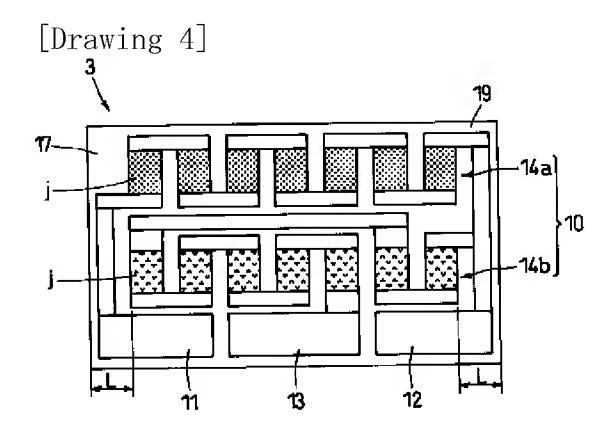
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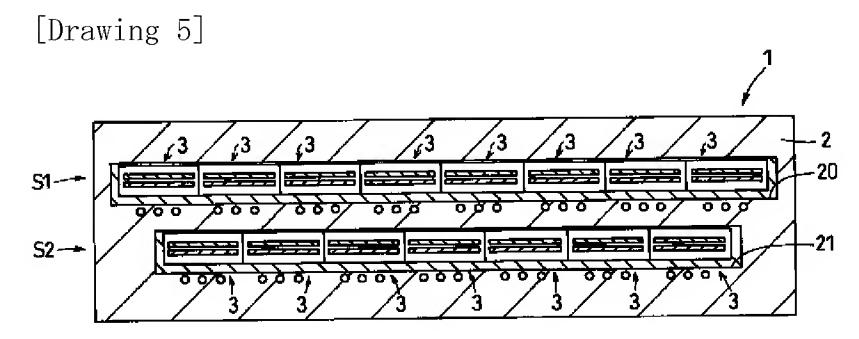


[Drawing 1]

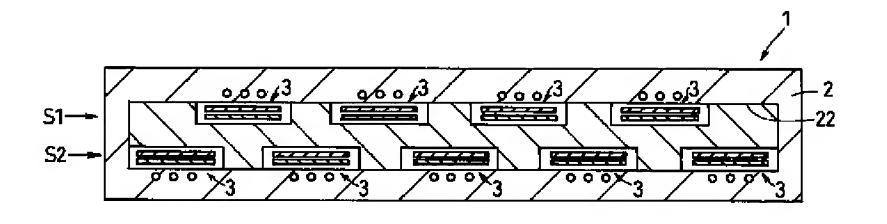


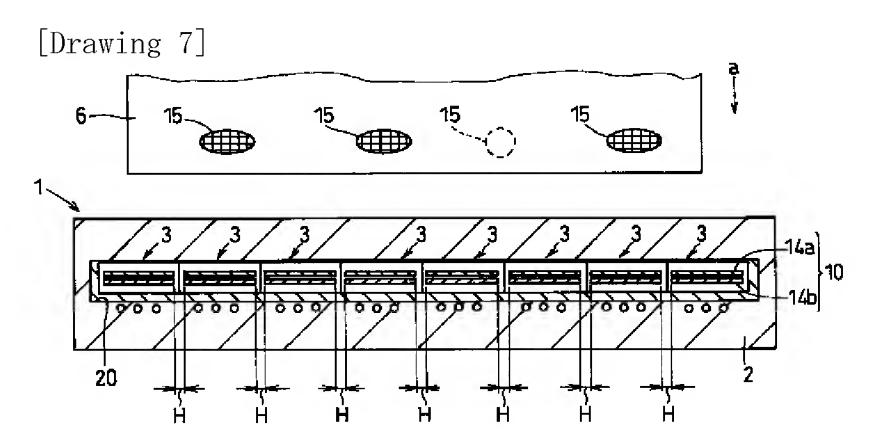






[Drawing 6]





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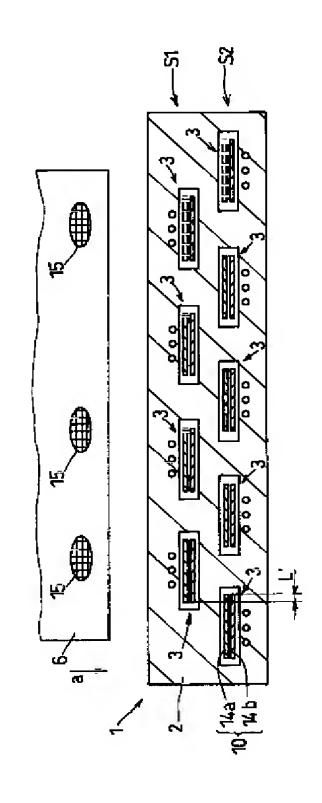
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(54) 【発明の名称】 磁気センサ

(57)【要約】

【課題】磁気センサにおいて、検出範囲の全範囲で磁気の読取を可能とし、磁気パターンの配列変更があっても、磁気パターン検知感度を高められ、また、クロストークが発生しないようにすること。

【解決手段】磁気パターン15を有する被検体6の通過方向に対して所定角度で交わる方向に沿って複数の磁気抵抗素子3を配列した素子列S1,S2を、被検体6の通過方向でずらして複数列設けるとともに、磁気抵抗素子3の配列方向で被検体6の通過する全領域が磁気感応領域となるように、一つの素子列における各磁気抵抗素子3は、他の素子列における磁気抵抗素子3に対して被検体6の通過する方向で磁気感応領域10が互いに重なる配列形態とされている。



【特許請求の範囲】

【請求項1】 磁気パターンを有する被検体の通過方向に対して所定角度で交わる方向に沿って複数の磁気抵抗素子を配列した素子列を、前記被検体の通過方向でずらして複数列設けるとともに、

一つの前記素子列における各磁気抵抗素子は、他の素子 列における磁気抵抗素子に対して前記被検体の通過する 方向で磁気感応領域が互いに重なる配列形態とされてい る、ことを特徴とする磁気センサ。

【請求項2】 請求項1に記載の磁気センサにおいて、 前記素子列は二列であり、

前記二列の素子列の一方における各磁気抵抗素子それぞれの磁気感応領域と、前記二列の素子列の他方における各磁気抵抗素子それぞれの磁気感応領域とは、前記被検体の通過する方向において互いに重なる配列形態とされている、ことを特徴とする磁気センサ。

【請求項3】 請求項1または2に記載の磁気センサにおいて、

前記磁気センサはケースを有しており、

前記ケースには、前記各素子列を構成する複数の磁気抵抗素子それぞれを個別に収納する複数の個別収納溝が設けられており、前記各個別収納溝に前記各素子列の磁気抵抗素子それぞれが収納されている、ことを特徴とする磁気センサ。

【請求項4】 請求項1または2に記載の磁気センサにおいて、

前記磁気センサはケースを有しており、

前記ケースには、前記各素子列ごとに、各素子列を構成する複数の磁気抵抗素子を共通収納する共通収納溝が設けられており、前記各共通収納溝それぞれに前記各素子列の磁気抵抗素子それぞれが収納されている、ことを特徴とする請求項1に記載の磁気センサ。

【請求項5】 請求項1から4のいずれかに記載の磁気 センサにおいて、

前記素子列で磁気抵抗素子の配列される方向と前記被検 体の通過方向とが交わる所定角度は、直交ないしはほぼ 直交する角度である、ことを特徴とする磁気センサ。

【発明の詳細な説明】

[0001]

【発明の属する技術分野】本発明は、磁気センサに係り、より詳しくは、磁気検出される被検体の通過方向に対して所定角度で交わる方向、例えば、直交する方向に沿って複数の磁気抵抗素子が配列されている磁気センサに関する。

[0002]

【従来の技術】図7を参照して、磁気センサ1と、この 磁気センサ1により検知されるべき被検体としての磁気 カード6とについて説明する。

【0003】磁気カード6は、図7に例示したものにおいて、磁気センサ1の検知面の長手方向に沿うよう対応

した複数の磁気パターン15を有する。この磁気パターン15は、磁気カード6に記録されるデータに対応する。

【0004】磁気センサ1は、同じくその検知面の長手 方向に沿って前記磁気パターン15を読取可能に配置し た複数の磁気抵抗素子3を有する。

【0005】磁気カード6が、図7の矢印a方向に移動して磁気センサ1に接近し、その検知面上を通過するとき、磁気センサ1の各磁気抵抗素子3それぞれは、磁気カード6の各磁気パターン15それぞれに個別に磁気感応し、その磁気感応に対応した検知出力を出力する。磁気センサ1の各検知出力は、信号処理する不図示の処理回路に与えられ、これによって、磁気カード6の記録データが処理される。

【0006】このような磁気カード6における個々の磁気パターン15と、磁気センサ1における個々の磁気抵抗素子3との配列間隔は、所定の関係にされ、磁気カード6に磁気パターン15の形態で記録されているデータを磁気センサ1で検知できるようにされている。

【0007】このような構造においては、隣合う磁気抵抗素子間の間隔が大きいと、磁気カード6における磁気パターン15の配列間隔に変化が生じた場合、その磁気パターン15と磁気センサ1における磁気抵抗素子3との対応関係が崩され、磁気センサ1は、磁気カード6の磁気パターン15を正確に検知することができなくなる。

【0008】そこで、本願出願人は、このように磁気パターンの配列間隔が変更されたとしても、各磁気パターンを確実に検知できる磁気センサを特開平5-332703号公報において既に提案している。

【0009】この磁気センサは、図7で示すように、ケース2の検知面となる一面の中央部付近に、長辺がケース2と同方向に沿う長溝20を設け、この長溝20に複数個の磁気抵抗素子3を、長辺方向一直線上に互いに当接するよう隣り合う形態で配列して構成されている。

【0010】このとき、隣り合う各磁気抵抗素子3,3 における磁気感応部10,10同士の間隔が、磁気パタ ーン15の幅より狭くなるように配列することで、磁気 カードの磁気パターンが変更されても、その磁気パター ンを検知することが期待できる。

[0011]

【発明が解決しようとする課題】ところで、本願出願人は、上記磁気センサの改良を図るため、さらに研究を重ね、その磁気センサに関して以下に説明する課題を見出した。

【0012】上記磁気センサ1に使用される各磁気抵抗素子3の磁気感応部10は、例えば、図4で示すように、複数個の単位感磁部jを直列接続した状態で左右方向に並設して感磁体列14a,14bを構成し、さらにこの感磁体列14a,14bの一対を、前後に互いに所

定間隔を隔てて基板17上に形成したものである。

【0013】しかしながら、図4に示すように、各磁気抵抗素子3において、磁気感応部10の左右方向での端部と基板17の左右方向での端縁部との間の領域には、感磁して磁電変換する構造がないことから、その領域は、磁気パターン15の検知が行なえない磁気不感応領域しとなっている。

【0014】そのため、この磁気抵抗素子3を上記磁気センサのように左右方向一列で配置させると、磁気抵抗素子3の磁気不感応領域L(例えば125μm程度の長さで磁気不感応領域が生じる)とこの磁気抵抗素子3と隣り合う磁気抵抗素子3の磁気不感応領域Lとが合計されて相当に大きな磁気不感応領域H(図7参照)が形成されることになる。

【0015】一方、磁気カード6の磁気パターン15の配列間隔や、磁気パターンと磁気抵抗素子3との対応位置関係が変更されると、例えば、図7に示すように、磁気カード6における磁気パターン15の位置が磁気感応部10に正対する実線位置から正対しない破線位置にずれるようなことが発生する。その結果、磁気センサによる磁気パターンの検知出力が低下し検知感度が低くなるおそれがある。

【0016】また、この磁気センサの場合、磁気抵抗素子が検知面の長手方向一列に配列されているから、磁気パターンが横方向に隣り合う磁気抵抗素子間にまたがるように接近した場合、両磁気抵抗素子それぞれから同一の磁気パターンに対する検知出力が同時に磁気カードデータ処理回路に与えられるいわゆるクロストークが発生し、この処理回路での磁気カードの記録データの処理に不具合を来たす。

【0017】したがって、本発明は、磁気センサにおいて、検出範囲の全範囲で磁気の読取を可能とし、磁気パターンの配列変更があっても、磁気パターン検知感度を高められ、また、前記クロストークが発生しないようにすることを解決すべき課題としている。

[0018]

【課題を解決するための手段】本発明は、磁気パターンを有する被検体の通過方向に対して所定角度で交わる方向に沿って複数の磁気抵抗素子を配列した素子列を、前記被検体の通過方向でずらして複数列設けるとともに、一つの前記素子列における各磁気抵抗素子は、他の素子列における磁気抵抗素子に対して前記被検体の通過する方向で磁気感応領域が互いに重なる配列形態とされていることを特徴とする。

【0019】本発明によると、被検体の通過方向でずらして配置された複数列の素子列における各磁気抵抗素子 それぞれの磁気感応領域は、被検体の通過する方向において互いに重なる配列形態とされていることで、磁気抵抗素子の配列方向で被検体が通過する全領域が磁気感応領域となるから、例え、被検体の磁気パターンの配列間 隔が変更されても、その磁気パターンを検知できる。したがって、検知出力の低下や検知感度の低下を来たすようなことがない。

【0020】また、前記各素子列が前記検知方向に対して所定距離ずらされて設けられているから、各素子列の磁気抵抗素子が同時に被検体を検知するクロストークが発生するようなことがなくなり、磁気パターンの検知を確実に行うことができるようになる。

【0021】本発明は、好ましくは、前記素子列は二列であり、前記二列の素子列の一方における各磁気抵抗素子それぞれの磁気感応領域と、前記二列の素子列の他方における各磁気抵抗素子それぞれの磁気感応領域とは、前記被検体の通過する方向において互いに重なる配列形態とされている。

【0022】この場合、素子列が二列であることで、被 検体の磁気パターンの配列間隔が変更されても、その磁 気パターンを確実に検出できるものでありながら、構造 的に簡単なものとなるとともに、コンパクトに構成でき る。

【 0 0 2 3 】本発明は、好ましくは、前記磁気センサは ケースを有しており、前記ケースには、前記各素子列を 構成する複数の磁気抵抗素子それぞれを個別に収納する 複数の個別収納溝が設けられており、前記各個別収納溝 に前記各素子列の磁気抵抗素子それぞれが収納されてい る。

【0024】本発明は、好ましくは、前記磁気センサはケースを有しており、前記ケースには、前記各素子列ごとに、各素子列を構成する複数の磁気抵抗素子を共通収納する共通収納溝が設けられており、前記各共通収納溝それぞれに前記各素子列の磁気抵抗素子それぞれが収納されている。

【0025】本発明は、好ましくは、前記素子列で磁気 抵抗素子の配列される方向と前記被検体の通過方向とが 交わる所定角度は、直交ないしはほぼ直交する角度であ る。

[0026]

【発明の実施の形態】以下、本発明の詳細を図面に示す 実施の形態に基づいて説明する。

【0027】図1ないし図4は、本発明の実施形態に係り、図1は、本実施の形態の磁気センサの斜視図、図2は、図1のA-A線に沿う断面図、図3は、図1のB-B線に沿う断面図、図4は、磁気抵抗素子の平面図である。

【0028】図1ないし図4を参照して、本実施の形態の磁気センサ1は、長尺型のケース2と、複数の磁気抵抗素子3…と、金属製カバー4と、バイアス用の永久磁石5とを有する。

【0029】ケース2は、被検体としての磁気カード6 が通過する方向に対して直交もしくはほぼ直交する方向 (後述する配列方向)に長尺な形状を有する。ケース2の 一面には複数の磁気抵抗素子収納溝7が設けられ、この収納溝7にそれぞれ磁気抵抗素子3が収納固定される。 この磁気抵抗素子収納溝7の深さは、磁気抵抗素子3の 素子厚みより深くされている。

【0030】ケース2の他面側には永久磁石収納溝8が設けられ、この収納溝8に単一の永久磁石5が収納固定される。

【0031】ケース2の一面側は、金属製カバー4で覆 われる。さらに、ケース2には複数の端子ピン9が貫通 固定されている。

【0032】この磁気抵抗素子3は、図4に示すように、内部に磁気感応部10を有し、その磁気感応部10の両端それぞれに接続電極を介して入出力用の端子11,13が接続され、前記両接続電極を中間接続する電極にも中間端子12が接続され、各3本の端子11,12,13が磁気抵抗素子3毎の検知方向片側に位置付けれられている。

【0033】詳述すると、磁気感応部10は、図4に示すように、2列の感磁部14a,14bが相対向する状態で設けられたものであって、一方の感磁部14aの両端には前記端子11,12がそれぞれ接続され、他方の感磁部14bの一端には前記端子13が接続され、他方の感磁部14bの他端には前記端子12が接続されている。

【0034】そして、各端子11,12,13に接続されるリード端子16,17,18は、ケース2に設けられた前記端子ピン9にそれぞれ接続されている。

【0035】これによって、この磁気センサ1は、複数の磁気抵抗素子3それぞれから被検体としての磁気カード6からの磁気情報の検知出力が個別に得られるようになっている。

【0036】以上の構成において、本実施の形態では、次の構成に特徴を有する。すなわち、本実施の形態では、複数の磁気抵抗素子収納溝7が、磁気カード6の磁気センサ1に対する通過する方向に対して直交する方向に所定間隔へだてて2列にずらされて千鳥状に位置設定されて設けられている。そして、前記千鳥状において各列の磁気抵抗素子収納溝7は、磁気カード6が磁気センサ1の検知面上を通過する方向において以下の関係で重なるように設けられている。

【0037】すなわち、図1および図2に示すように、各素子列の磁気抵抗素子収納溝7それぞれに磁気抵抗素子3が収納されていることにより、前記複数の磁気抵抗素子3は、それぞれ所定数の磁気抵抗素子でもって2つの素子列S1、S2に分けられ、各素子列S1、S2において一方の素子列S1における二つの磁気抵抗素子3、3それぞれの磁気感応部10、10に対して、他方の素子列S2における磁気抵抗素子3の磁気感応部10が磁気カード6が磁気パターン15の検出のため磁気センサ1を通過する方向(図2における矢印aの示す方

向)において重なる配列形態とされている。

【0038】ここで、磁気抵抗素子1は、図4で示すように、所要の基板19上に磁気感応部10が前記所定方向に沿って形成されており、基板19の前記所定方向における両端縁と磁気感応部10の長手方向両端縁それぞれの間の領域が磁気不感応領域Lとなっている。また、各素子列内において所定方向において隣り合う磁気抵抗素子の両磁気感応部の対向距離は、被検体としての磁気カード6の検知長さ(つまり磁気パターン15が設けられている範囲の長さ)以下に設定されている。ここで、磁気感応部10は、磁気感応領域を示す。

【0039】そのうえで、一方の素子列S1における二つの磁気抵抗素子3,3それぞれの磁気感応部10,10に対して、他方の素子列S2における磁気抵抗素子3の磁気感応部10が磁気カード6の磁気センサ1を通過する方向において重なる配列形態とされている。

【0040】したがって、本実施の形態に係る磁気センサ1の場合、磁気抵抗素子3が所定方向に隣り合って複数配置され、それらの磁気不感応領域により当該所定方向に大きな磁気不感応領域が形成されて、かつ、磁気カード6側で磁気パターン15の配列間隔が変更されても、一方の素子列における二つの磁気抵抗素子それぞれの磁気感応部10に対して、他方の素子列における磁気抵抗素子の磁気感応部10が前記磁気カード6の通過方向に対して重なる配列形態により、磁気カード6の磁気パターン15の通過する横幅範囲の全体において、その磁気パターン15の検出不能な領域がないので、その磁気パターン15を確実に精度良く検知できる。特に、各列S1、S2間の磁気感応部10が重なる領域し、が検出パターン上にある場合でも、検知出力の低下や検知感度の低下を来たすようなことがない。

【0041】また、前記各素子列S1,S2が磁気カード6の前記通過方向に対して所定距離ずらされて設けられているから、各素子列S1,S2の磁気抵抗素子3が同時に被検体を検知するクロストークが発生するようなことがなくなり、磁気パターン15の検知を確実に行うことができるようになる。

【 0 0 4 2 】本発明は、上述の実施形態に限定されるものではなく、種々な応用や変形が考えられる。

【0043】(1)上述の実施形態の場合、磁気抵抗素子収納溝は各磁気抵抗素子それぞれを個別に収納する個別収納溝であったが、図5で示すように、一方の素子列を構成する複数の磁気抵抗素子3を共通収納する共通収納 溝20と、前記他方の素子列を構成する複数の磁気抵抗素子3それぞれを共通収納する共通収納溝21とが長手方向に所定距離位置ずれさせて設けられており、前記各共通収納溝20,21それぞれに前記各素子列S1,S2の磁気抵抗素子3それぞれが収納されているものでもよい。この場合、各素子列S1,S2において磁気抵抗素子3が隣合うもの同士がスペーサなどなく互いに当接

するように収納しているとともに、共通収納溝20,2 1がその長手方向で所定距離位置ずれしていることで、 被検体が矢印a方向に移動して磁気検出のため磁気セン サ1を通過していく際に、その通過方向で素子列S1の 磁気抵抗素子3の磁気感応領域となる磁気感応部10 と、素子列S2の磁気抵抗素子3の磁気感応領域となる 磁気感応部10とが重なるため、磁気抵抗素子3が配列 されている方向での被検体の通過領域において磁気検出 できない領域はなくなり、精度良く磁気検出できる。

【0044】(2)上述の実施形態の場合、磁気センサのケースは、長尺となっているが、これに限定される必要はなく、磁気抵抗素子を収納できるケースであればよい。

【0045】(3)上述の実施形態の場合、磁気抵抗素子は、被検体の通過方向に対して直交する方向に配列されて素子列を構成しているが、その素子列の方向は被検体の通過方向に対して直交する必要は必ずしもなく、被検体の通過方向に対して斜めとなる所定の角度で交わるものでもよい。

【0046】(4)上述の実施形態の場合、1つの磁気抵抗素子収納溝には1つの磁気抵抗素子が収納される形態となっているが、1つの磁気抵抗素子収納溝に1つの磁気抵抗素子を収納させる必要は必ずしもなく、例えば、図6で示すように、1つの磁気抵抗素子収納溝22に複数の磁気抵抗素子3…を収納させるようにしてもよい。この場合、素子列S1、S2間、並びに、同じ素子列における隣合う磁気抵抗素子3間にはスペーサを介在させることになる。

【0047】(5)上述の実施形態の場合、上記磁気センサ1に使用される各磁気抵抗素子3の磁気感応部10は、例えば、図4で示すように、複数個の単位感磁部方を直列接続した状態で左右方向に並設して感磁体14a,14ba,14bを構成し、さらにこの感磁体14a,14bの一対を、前後に互いに所定間隔を隔てて基板17上に形成したものを示したが、感磁体が横にひとつながりとなるように構成した磁気抵抗素子でも良い。

【0048】(6)上述の実施形態の場合、被検体として、磁気カードについて示したが、磁気カードに限定されるものでなく、例えばスティック状の磁気記録媒体などでも良い。

【0049】(7)上述の実施形態では、各素子列内において所定方向において隣り合う磁気抵抗素子の両磁気感応部の対向距離は、被検体としての磁気カード6の検知長さ以下に設定されているとしたが、必ずしもこのように設定する必要はなく、その対向距離が被検体の検知長さより長い場合も本願発明に含まれる。

[0050]

【発明の効果】以上説明したように、本発明によれば、 非検知エリアがなくなるため、例え、磁気パターンの配 列変更があっても、磁気パターン検知感度を高められ、 検出範囲の全範囲において磁気の読取が可能となる。ま た、クロストークが発生しないようにすることができ る。

【図面の簡単な説明】

【図1】本発明の実施形態に係る磁気センサの斜視図

【図2】図1のA-A線に沿う断面図

【図3】図1のB-B線に沿う断面図

【図4】磁気抵抗素子の平面図

【図5】本発明の他の実施形態に係る磁気センサの要部 の平面図

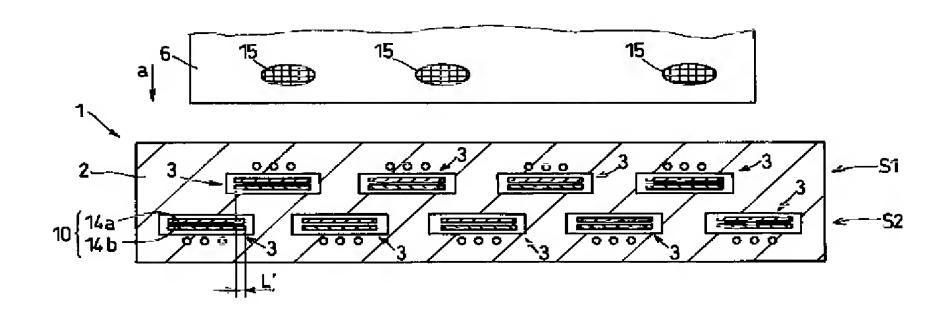
【図6】本発明の他の実施形態に係る磁気センサの要部の平面図

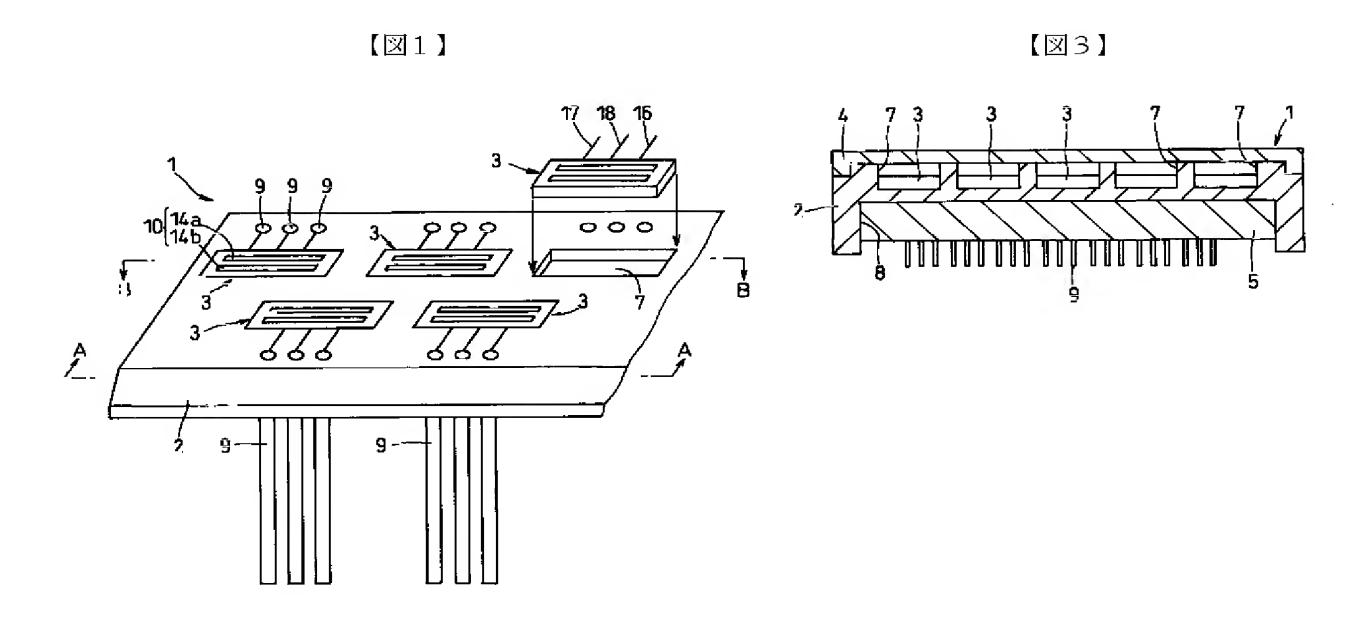
【図7】磁気カードと従来の磁気センサとの関係を示す 図

【符号の説明】

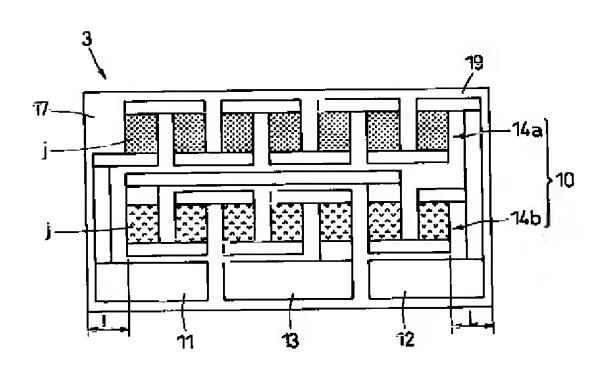
- 1 磁気センサ
- 3 磁気抵抗素子
- 6 磁気カード(被検体)
- 10 磁気感応部(磁気感応領域)
- 15 磁気パターン
- S1, S2 素子列

【図2】

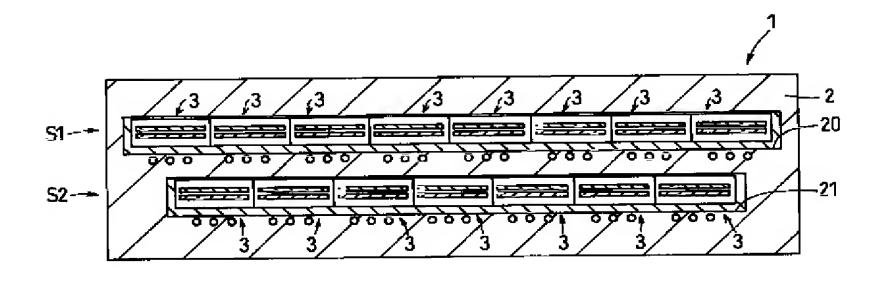




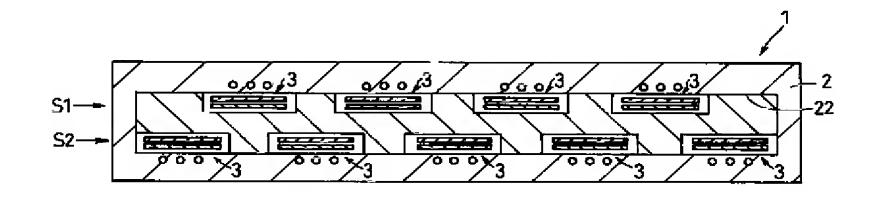
(34)



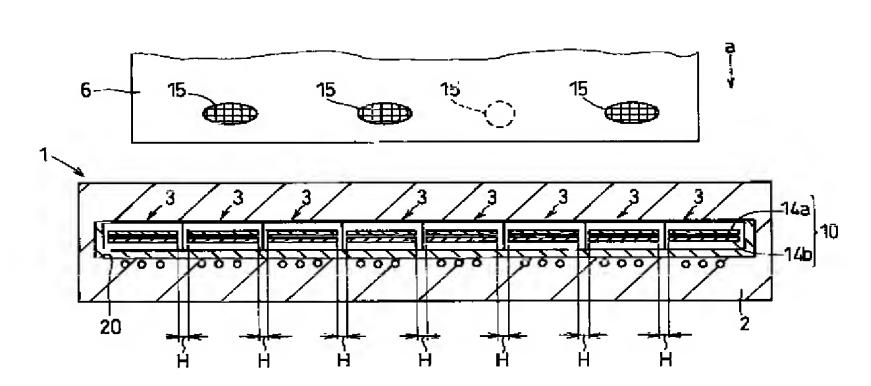
【図5】



【図6】



【図7】



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